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TRANSMITTAL FORM <i>(to be used for all correspondence after initial filing)</i>	Application Number	09/955,810
	Filing Date	September 19, 2001
	First Named Inventor	Yoshiyuki Tanaka, et al.
	Art Unit	2825
	Examiner Name	Lee Calvin
Total Number of Pages in This Submission	Attorney Docket Number	075834.00111

ENCLOSURES (Check all that apply)		
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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

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Applicants: Yoshiyuki Tanaka et al. **Atty. Docket No.** 075834.00111
Serial No.: 09/ 955,810 **Group Art Unit:** 2825
Filed: September 19, 2001 **Examiner:** Lee Calvin
Invention: "PRODUCTION METHOD OF SEMICONDUCTOR DEVICE"

AMENDMENT B

Assistant Commissioner of Patents
Alexandria, VA 22313-1450

S I R:

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In response to the Office Action dated May 21, 2003, please amend the application as follows:

IN THE CLAIMS:

1. (Previously Amended) A method for producing a semiconductor device including formation of an interlayer insulating film having a fluorine-doped silicon oxide layer above a substrate, the method comprising the steps of:

forming said fluorine-doped silicon oxide layer in a process chamber; and

forming a silicon oxide layer on said fluorine-doped silicon oxide layer in a same process chamber subsequent to formation of said fluorine-doped silicon oxide layer, said silicon oxide layer being formed at a temperature at least 10% higher than a film forming temperature of said fluorine-doped silicon oxide layer; thereby

forming said interlayer insulating film comprising said fluorine-doped silicon oxide layer and said silicon oxide layer formed thereon.

2. (Original) The method for producing a semiconductor device according to claim 1, wherein

a film forming temperature of said silicon oxide layer is equal or less than 450 °C.

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